ITW/AF

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| In re Applicant: | | § | |
| | Randy Skocypec et al. | § | Art Unit: 1746 |
| | | § | |
| Serial No.: | 10/622,307 | § | Examiner: Bibi Sharidan Carrillo |
| | | § | |
| Filed: | July 18, 2003 | § | Docket: ITL.1017US |
| | | § | P16704 |
| For: | Cleaning Semiconductor | § | |
| | Wafers | § | Assignee: Intel Corporation |
| | | § | |

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# REPLY BRIEF

In response to the new arguments set forth in the Examiner's Answer, the following Reply Brief is submitted.

With respect to the arguments about the "interface," the Applicants will rely on the Appeal Brief.

With respect to Figure 3C, t2, the Examiner is mistaken. At t2, in Figure 3C, the flow of scrubbing fluids has ceased. See the reference at column 10, lines 26-27. Therefore, there is no providing a cleaning solution through at least one of the brushes and there is no spraying a solution at the interface between said rotating brushes and said wafer.

When a solution is supplied into the brushes, this cannot constitute spraying the solution at the interface. In connection with solution supplied into the brushes, the brushes are "saturated with the scrubbing fluids 207a and 207b." See reference at column 10, lines 18-20. Thus, there is no spraying of a solution at the interface between the rotating brushes. Instead, solution is fed
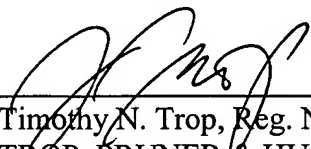
to the top of one brush and the bottom of the other.  See Figure 3C and the reference at column 10, lines 21-24.

In view of these remarks, the rejections should be reversed.

Respectfully submitted,

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